



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. .... 09/212,726  
Filing Date ..... December 15, 1998  
Inventor..... Klaus F. Schuegraf  
Assignee..... Micron Technology, Inc.  
Group Art Unit..... 2813  
Examiner ..... Kielin, Erik J.  
Attorney's Docket No. .... MI22-1098  
Title: Semiconductor Processing Methods of Chemical Vapor Depositing SiO<sub>2</sub> on a  
Substrate

**RESPONSE TO APRIL 19, 2002 OFFICE ACTION**

To: Assistant Commissioner for Patents  
Washington, D.C. 20231

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**AMENDMENTS**

**In the Claims**

Please replace the indicated claims with the following clean versions of the claims, in accordance with 37 C.F.R. § 1.121(c)(1)(i). Cancel all previous versions of any indicated claim. A marked up version showing amendments to any claims being changed is provided in one or more accompanying pages separate from this amendment in accordance with 37 C.F.R. § 1.121(c)(1)(ii). Any claim not accompanied by a marked up version has not been changed relative to the immediate prior version, except that marked up versions are not being supplied for any canceled claim.